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Avesha S. Wilks

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Michael Nuttall and

Attorney Docket No.: 500803.02

Garry Anthony Mercaldi

Serial No. : 10/075,640

Group Art Unit : 2818

: David Vu

: February 13, 2002

Examiner

Filed Title

: METHOD FOR ENHANCING VERTICAL GROWTH DURING THE SELECTIVE

FORMATION OF SILICON, AND STRUCTURES FORMED USING SAME

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Mail Stop RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F.R. §§ 1.56 and 1.97 through 1.98, applicants wish to make known to the Patent and Trademark Office the references set forth on the attached form PTO-1449. This application relies, under 35 U.S.C. § 120, on the earlier filing date of prior Application No. 09/770,909, filed January 26, 2001. The references listed on the attached Form PTO-1449 were submitted to and/or cited by the Patent and Trademark Office in this prior application and, therefore, are not required to be provided in this application. If the Examiner wishes, copies will be provided upon request. Although the aforesaid references are made known to the Patent and Trademark Office in compliance with applicants' duty to disclose all information they are aware of which is believed relevant to the examination of the above-identified application, applicants believe that their invention is patentable.

Please acknowledge receipt of this Supplemental Information Disclosure Statement and kindly make the cited references of record in the above-identified application.

Respectfully submitted,

DORSEY & WHITNEY LLP

Kimton N. Eng Registration No. 43,605

KNE:asw

Enclosures:

Postcard

Form PTO-1449

1420 Fifth Avenue, Suite 3400 Seattle, WA 98101 Telephone (206) 903-8800 Facsimile (206) 903-8820

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FORM PTO-1449 (REV.7-80)			U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMÂRK OFFICE		ATTY. DOCKET NO. 500803.02	APPLICATION NO. 10/075,640			
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TEXT			U.S	. PATENT I	DOCUMENTS				 .
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OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.) Boman, M. et al., "Helical Microstructures Grown by Laser Assisted Chemical Vapour									
	AN	Deposition", Micro Electro Mechanical Systems, February 4-7, 1992, pp. 162-167.							
	AO	Wallenberger, F.T., "Rapid Prototyping Directly from the Vapor Phase (Laser-assisted Chemical Vapor Deposition)", American Association for the Advancement of Science, March 3, 1995, pp. 1-5.							
	AP	Westberg, H. et al., "Truly Three Dimensional Structures Microfabricated by Laser Chemical Processing", IEEE, 1991, pp. 516-519.							
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